

	Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-918001	Application No. 10/799,435
	Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR 1.98(b))		Applicant Alexander Tregub et al.	
			Filing Date March 12, 2004	Group Art Unit 1773

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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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Sheet 1 of 1

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	AK						

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	AO							
	AP							

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Substitute Disclosure Form (PTO-1449)